

# Eu<sup>3+</sup> or Er<sup>3+</sup> doped Y<sub>2</sub>O<sub>3</sub> thin films grown by ALD with optimized properties for quantum technologies

M. Scarafagio<sup>1</sup>, A. Ferrier<sup>1</sup>, A. Tallaire<sup>1</sup>, K.J. Tielrooij<sup>2</sup>, D. Cano<sup>2</sup>, A. Reserbat-Plantey<sup>2</sup>, F. Koppens, M.-H. Chavanne<sup>1</sup>, A. Grishin<sup>1</sup>, M. Cassir<sup>1</sup>, P. Goldner<sup>1</sup>

1. Institut de Recherche de Chimie Paris (IRCP) PSL Research University, Chimie ParisTech
2. ICFO - Institut de Ciències Fotòniques, The Barcelona Institute of Science and Technology

3<sup>rd</sup> year PhD student / [marion.scarafagio@chimieparistech.psl.eu](mailto:marion.scarafagio@chimieparistech.psl.eu)

# Plan

Introduction

I. Towards ALD deposition of ultra-thin films and optical properties

II. Alternative ALD depositions: buffer layer and different substrates

Conclusions and perspectives

# Plan

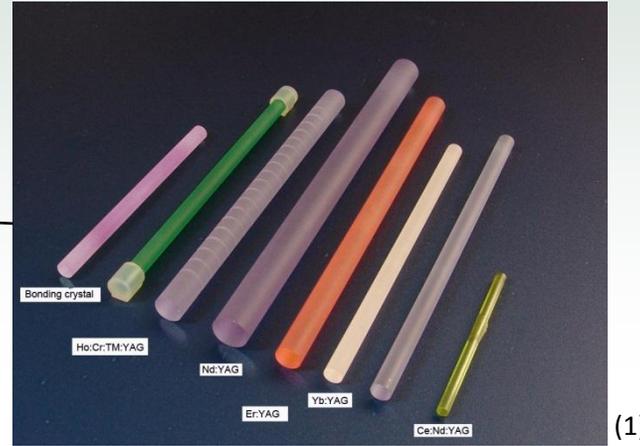
## Introduction

- I. Towards ALD deposition of ultra-thin films and optical properties
- II. Alternative ALD depositions: buffer layer and different substrates

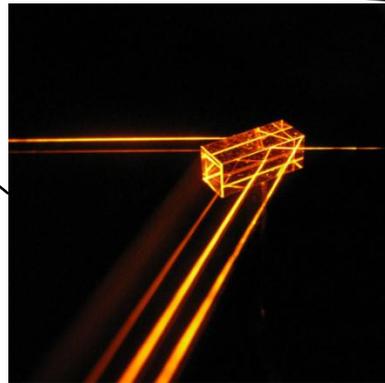
## Conclusions and perspectives

# Rare-Earth Doped Materials for Photonics

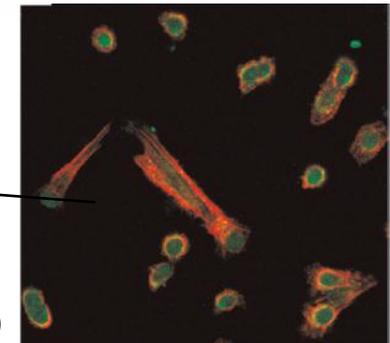
- Luminophores:  $\text{Y}_2\text{O}_3:\text{Eu}^{3+}$  (red color)
- Laser:  $\text{Y}_3\text{Al}_5\text{O}_{12}:\text{Nd}^{3+}$  (YAG)
- Scintillator:  $\text{YSO}:\text{Ce}^{3+}$
- Bioimaging (nanoparticles)
- **Quantum information**



(1)



(3)



(2)

$\text{Tb}^{3+}:\text{Y}_2\text{O}_3$  nanophosphors

**=> Specially designed high-grade materials**

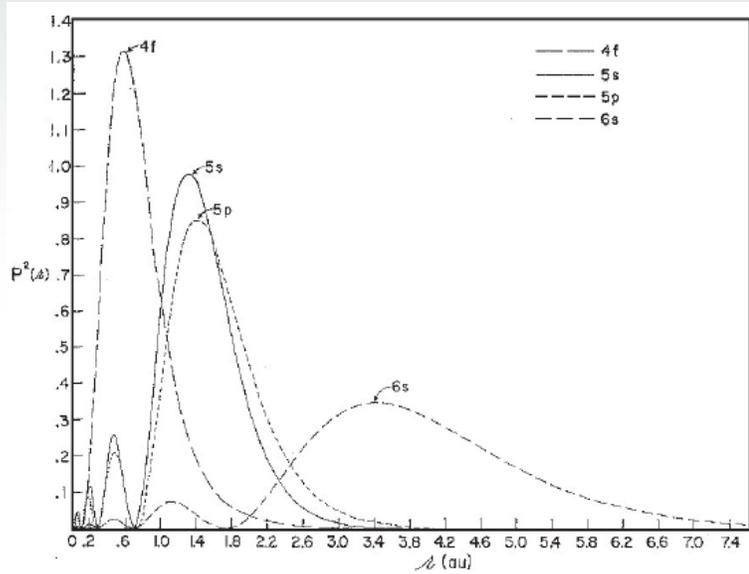
(1) <http://keywordhelp.cn.com/vs-yag>

(2) Sotiriou et al, *ACS Nano* 6, 5 (2012).

(3) Courtesy J. Bartolomew

# Rare Earth Ions Properties

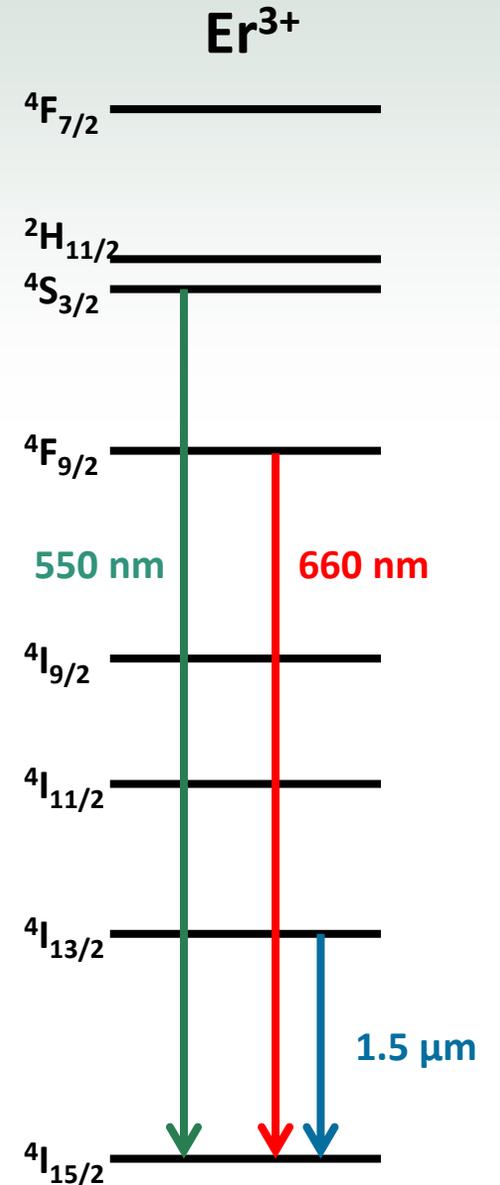
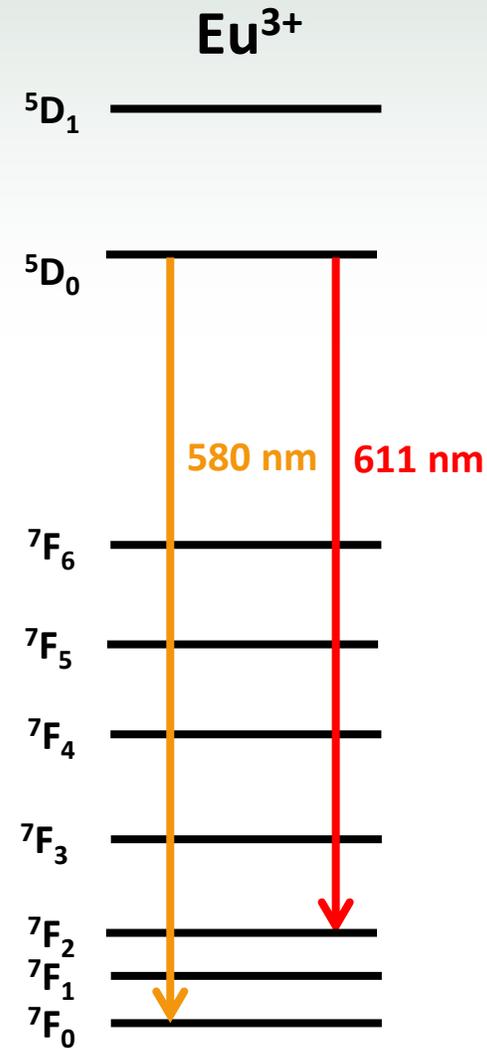
- Electronic configuration  $\text{Ln}^{3+}$  ion:  $[\text{Kr}]4f^n(5s^25p^6)$



(1)

- 4f layer protected from the outside, behave like a gas atom
  - ➔ Long coherence time for optical and spin transitions
- Wide range of frequencies from MHz to THz

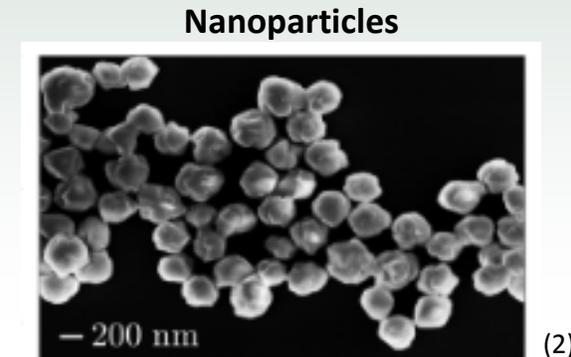
**Need for a host material**



# Objectives

- **Host material:**  $Y_2O_3$  = sesquioxide, cubic phase (ambient T and P)
- $Y_2O_3:Eu^{3+}$  = material with long coherence time:
  - Monocrystal:  $T_2 \approx 1$  ms
  - Transparent ceramic:  $T_2 \approx 100$   $\mu$ s (1)
  - Nanoparticles:  $T_2 \approx 7$   $\mu$ s (2)

  
<http://www.nanoqtech.eu/>



(2)

- Development of rare earth doped nanostructures for hybrid quantum systems  
→ **Thin films  $Eu^{3+}:Y_2O_3$  or  $Er^{3+}:Y_2O_3$  on Si(100) substrates**
- **Final goal:** obtain a high quality **ultrathin film** with properties as close as possible to the single-crystal  
→ Different couplings possible (photonic crystals, cavity, mechanical resonator...)

**Ultra-thin films with optimized optical properties => Atomic Layer Deposition (ALD)**

(1) N. Kunkel et al, *APL Materials*, 3 (2015).

(2) J. G. Bartholomew et al, *Nano. Lett.*, 17 (2017).

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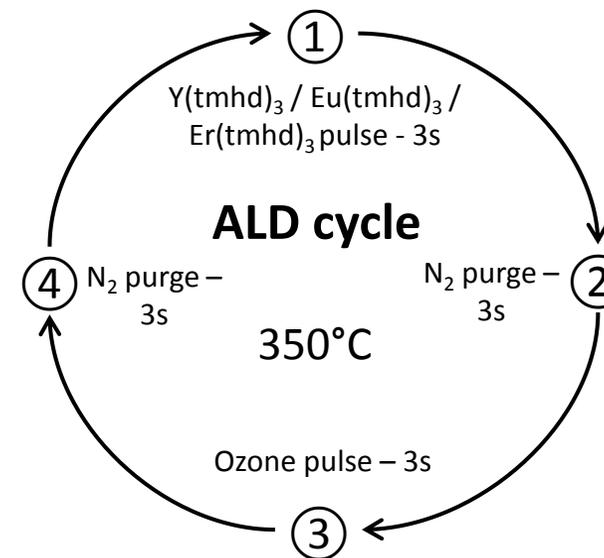
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# I. Towards ultra-thin films – ALD deposition

- Picosun Sunale R200 vertical flow type reactor
- $\text{Y}_2\text{O}_3:\text{Eu}^{3+}$  and  $\text{Y}_2\text{O}_3:\text{Er}^{3+}$  thin films (5 nm – 400 nm)
- $\text{Y}(\text{tmhd})_3$ ,  $\text{Eu}(\text{tmhd})_3$  and  $\text{Er}(\text{tmhd})_3$  precursors and  $\text{O}_3$
- Optimization of ALD parameters (deposition and precursors temperatures, ozone and purge pulse time,... )



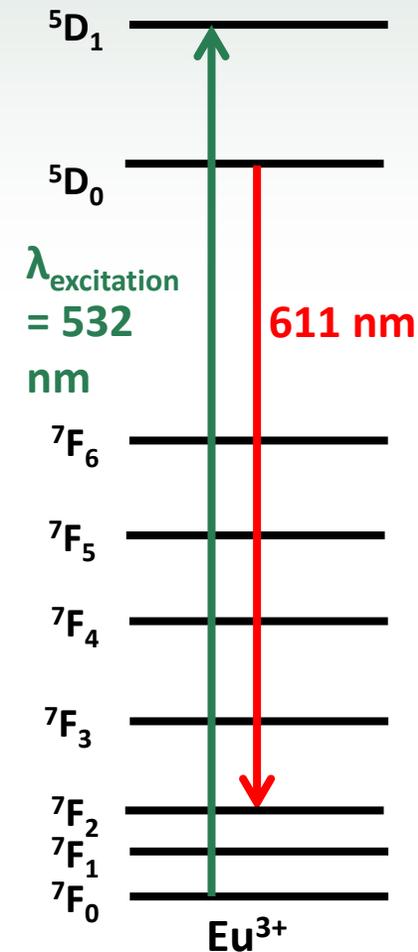
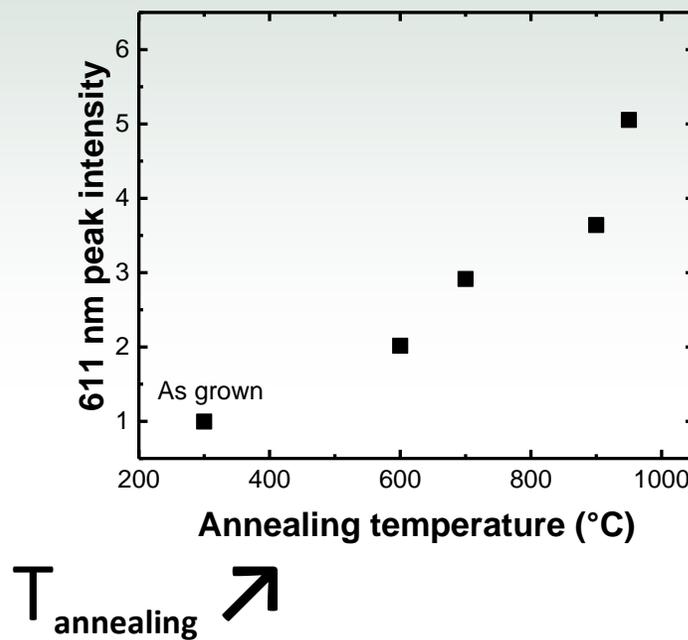
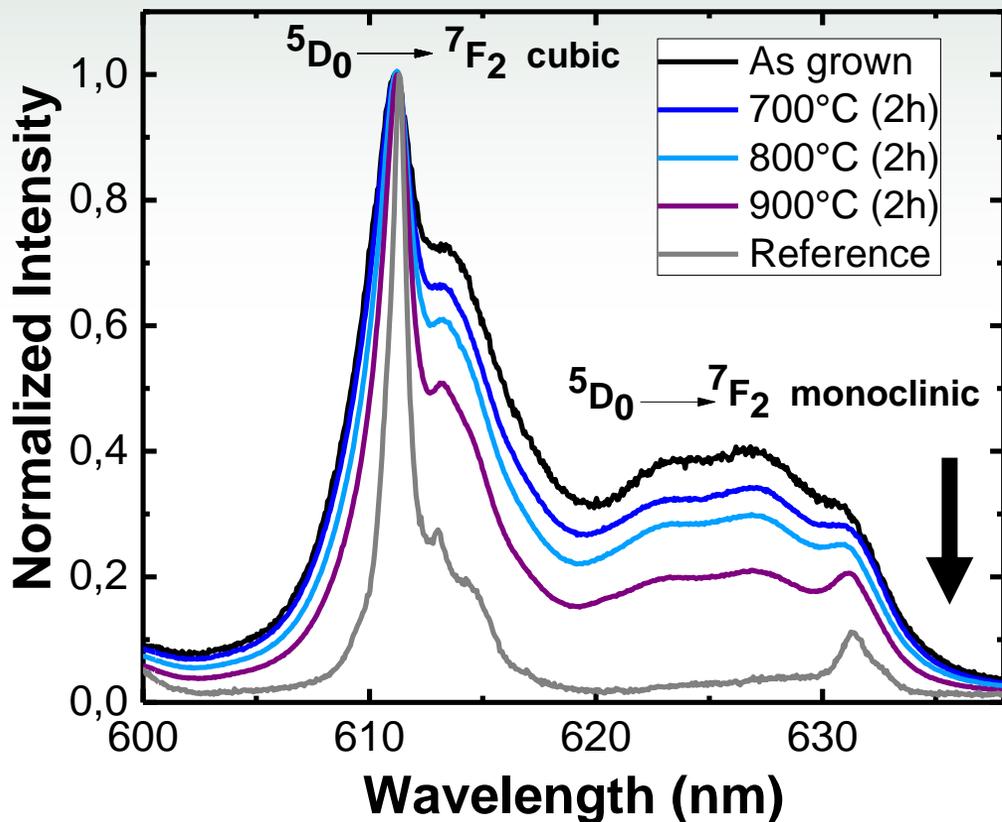
Yttrium oxide thin film doped with  $\text{Eu}^{3+}$  (thickness of 100 nm) on Si(100) elaborated by ALD



Scarafagio et al, *J. Phys. Chem. C*, 123 (2019).

# I. Room Temperature Photoluminescence

Thickness = 118 nm /  $\text{Y}_2\text{O}_3:\text{Eu}^{3+}$  (5%) / RT

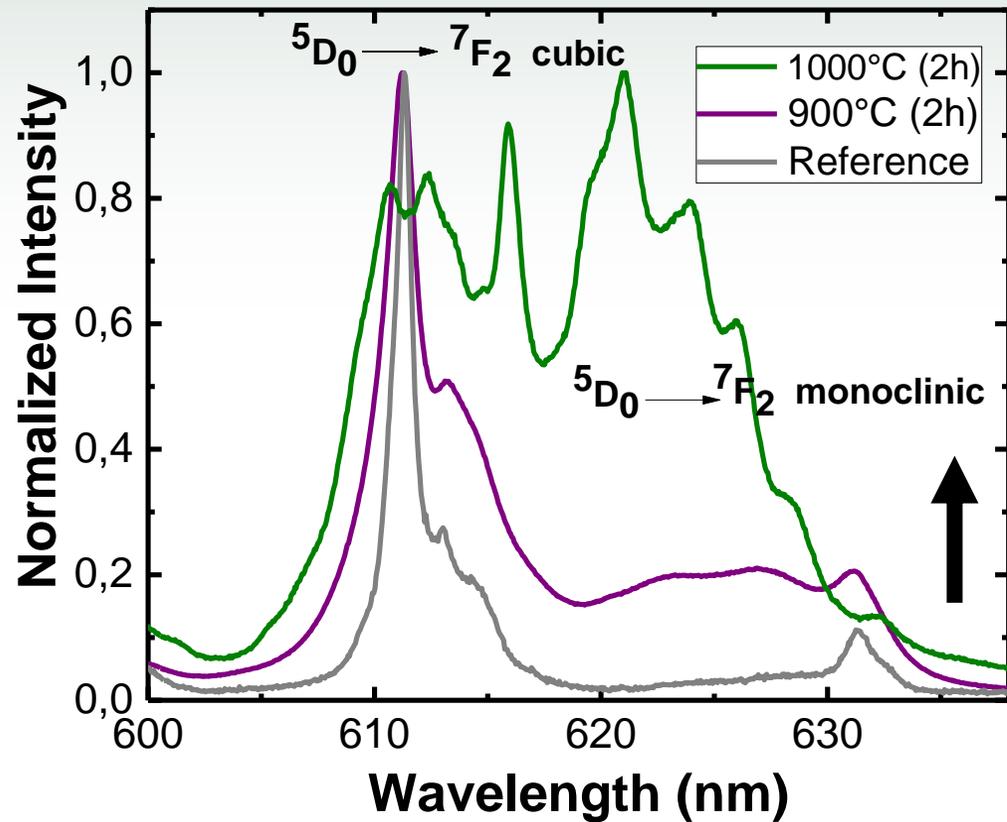


Annealing step required  $\rightarrow$  improvement of optical properties

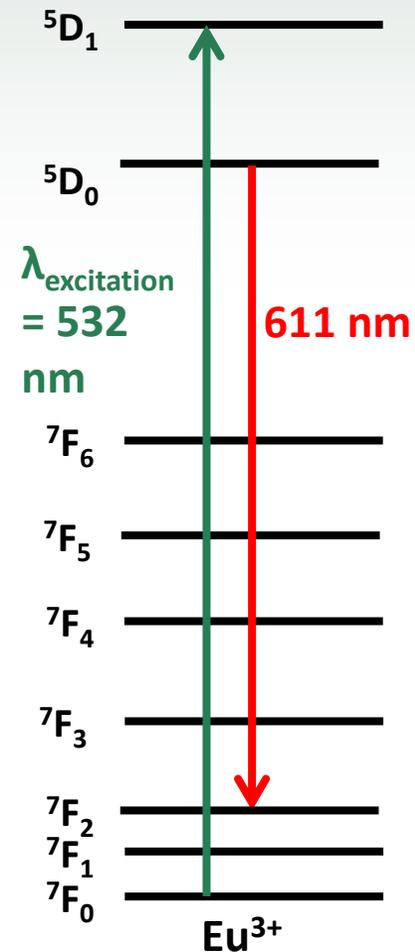
Scarafagio et al, *J. Phys. Chem. C*, 123 (2019).

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$T_{\text{annealing}}$  ↗

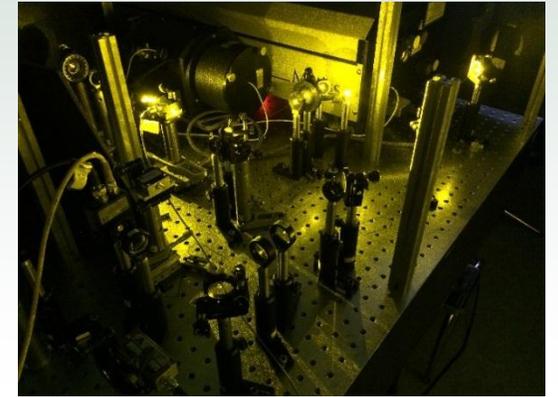
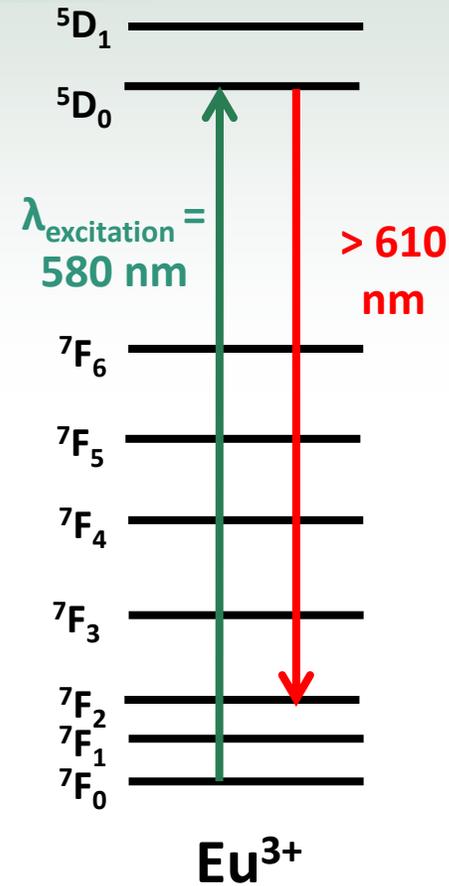
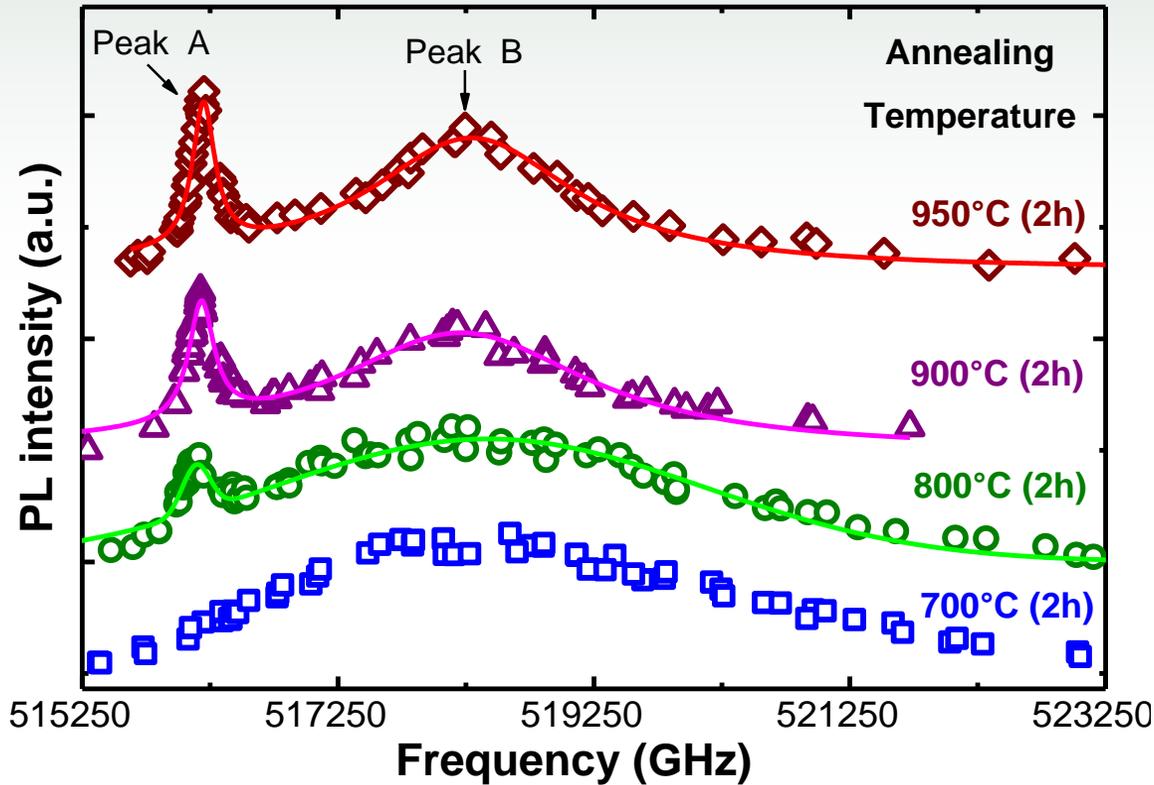


But above 1000°C new phases are formed (interfacial silicate)

Scarafagio et al, *J. Phys. Chem. C*, 123 (2019).

# I. Inhomogeneous linewidth (PLE)

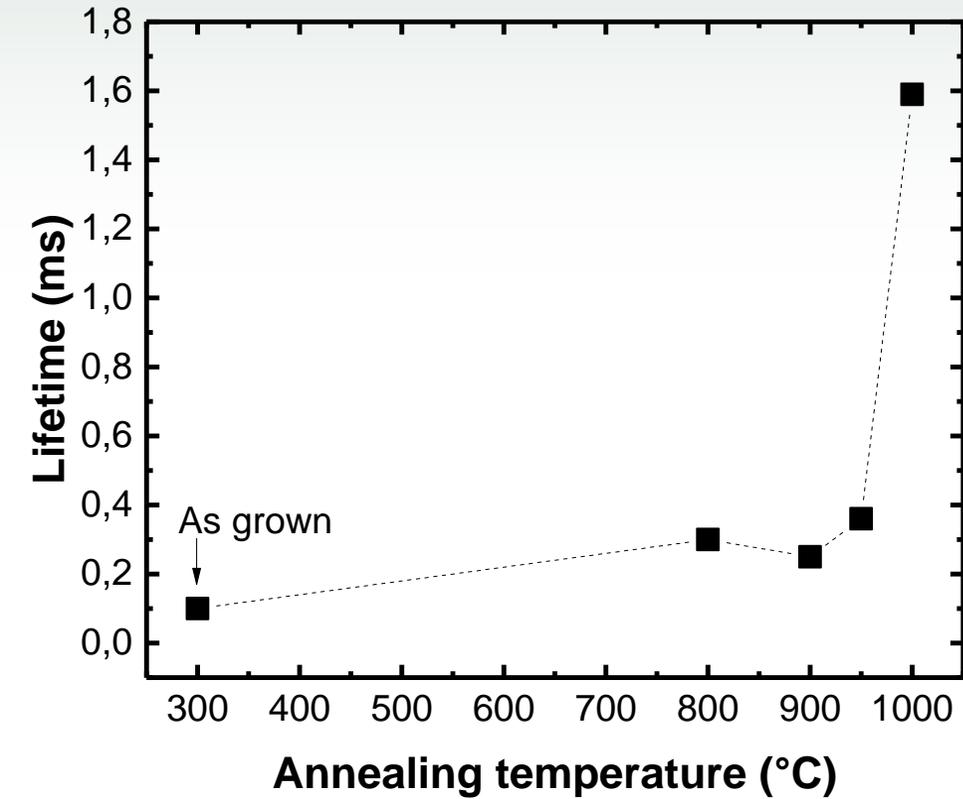
Thickness = 168 nm /  $\text{Y}_2\text{O}_3:\text{Eu}^{3+}$  (5%) /  $T = 10$  K



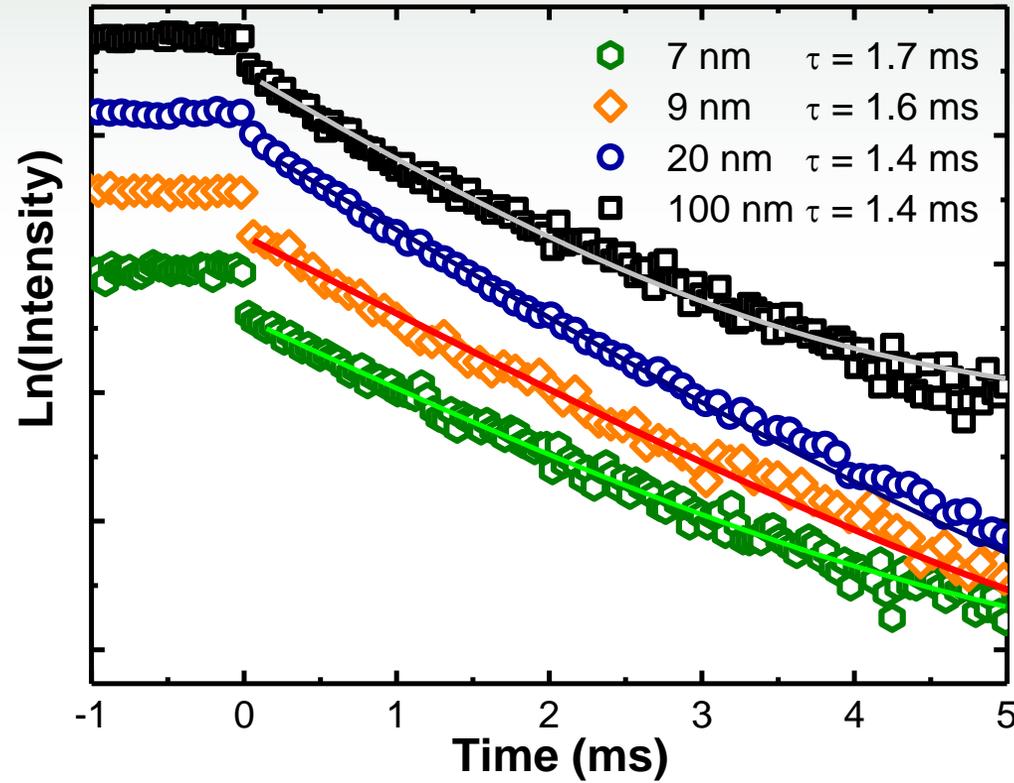
- **Peak A**  $\rightarrow$   $\text{Y}_2\text{O}_3:\text{Eu}^{3+}$  cubic phase; **Peak B**  $\rightarrow$  disorder + monoclinic phase
- Films:  $\Gamma_{\text{inh}} \approx 200$  GHz and Ceramic (reference):  $\Gamma_{\text{inh}} \approx 100$  GHz  $\rightarrow$  Impurities, defects and stress

# I. Ultra-Thin Films: 1.5 $\mu\text{m}$ $\text{Er}^{3+}$ Lifetime Measurements

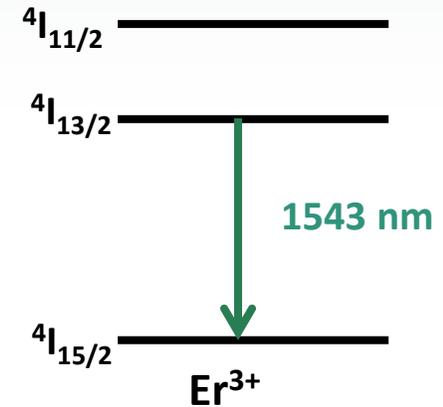
Thickness = 14 nm /  $\text{Y}_2\text{O}_3:\text{Er}^{3+}$  (2%) / RT



$\text{Y}_2\text{O}_3:\text{Er}^{3+}$  (2%) / RT / Annealing = 950°C (2h)



**ICFO**<sup>R</sup>  
The Institute of Photonic Sciences



- Improvement with annealing step
- Lifetime **still long** ( $> 1$  ms) when the thickness decreases
- **Reference:** 76  $\mu\text{s}$  for  $\text{Y}_2\text{O}_3:\text{Er}^{3+}$  (1 mol %) nanoparticles with a diameter of 100-150 nm (1)

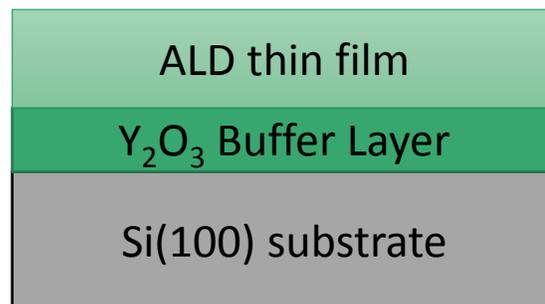
# I. Towards Ultra-Thin films – Summary

- Promising results but **limitations** with Si(100) substrates:
  - SiO<sub>2</sub> growth after annealing step at 900°C and above
  - New phases formation at 1000°C and above

Two alternative strategies

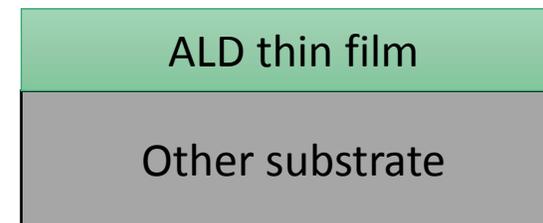
## Buffer Layer

- Increase the **distance** between the **emitting ions** and the **substrate**
- **Ex:** Y<sub>2</sub>O<sub>3</sub> grown by ALD, Y<sub>2</sub>O<sub>3</sub> grown by CVD...



## Other substrates

- **Refractory** substrates
- **Ex:** sapphire, transparent ceramic Y<sub>2</sub>O<sub>3</sub>



# Plan

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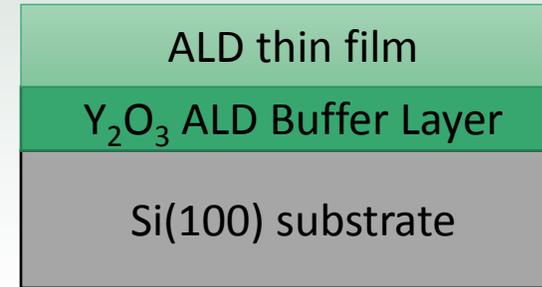
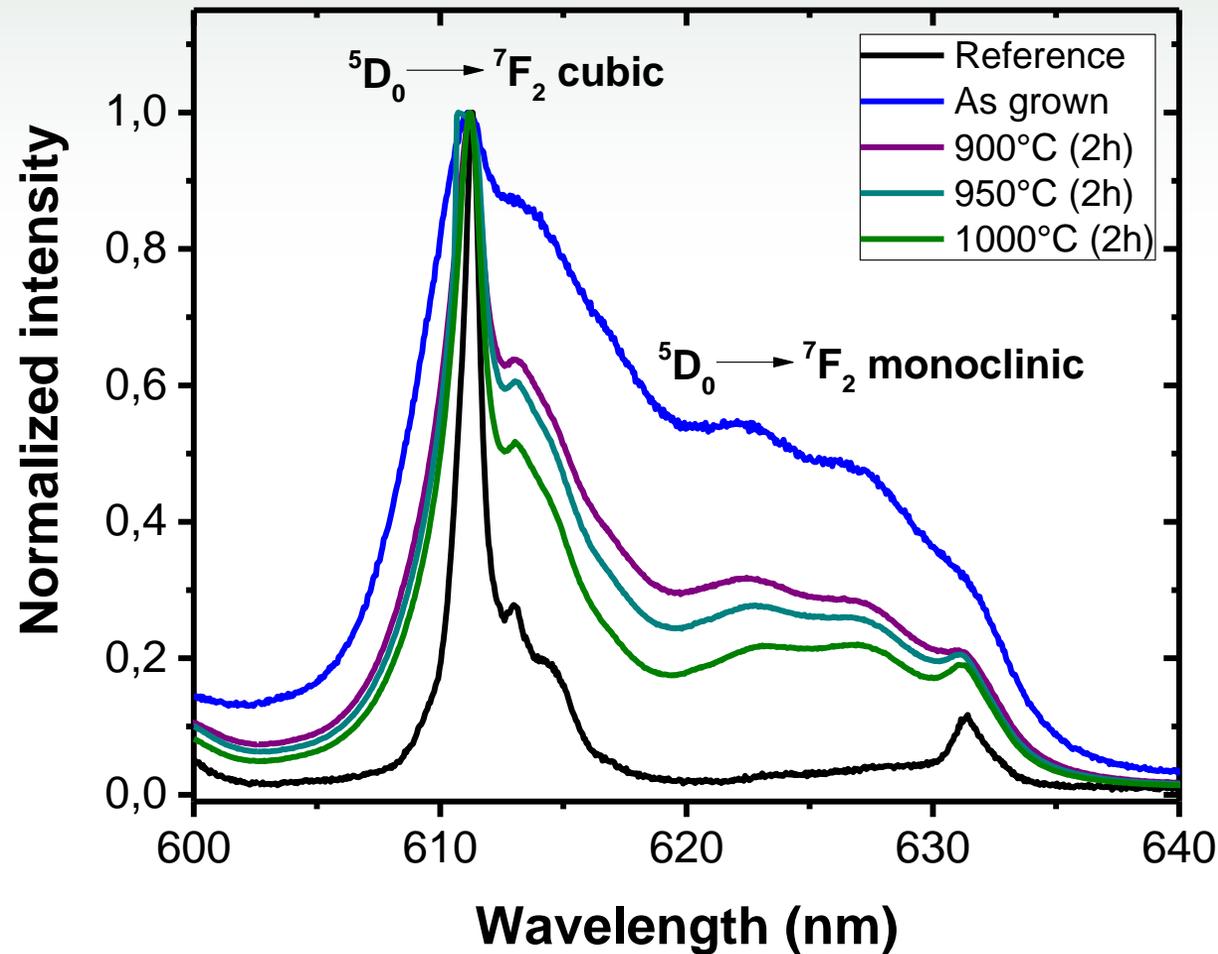
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# II. Alternative Depositions – ALD Buffer Layer

- Buffer layer =  $\text{Y}_2\text{O}_3$  grown by ALD



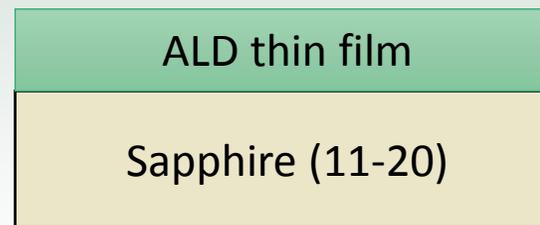
Thickness Film = 358 nm  
 $\text{Y}_2\text{O}_3:\text{Eu}^{3+}$  (5%)  
+ buffer  $\text{Y}_2\text{O}_3$

- Improvement of PL spectra when the annealing temperature increases
- **No parasitic phases at 1000°C**

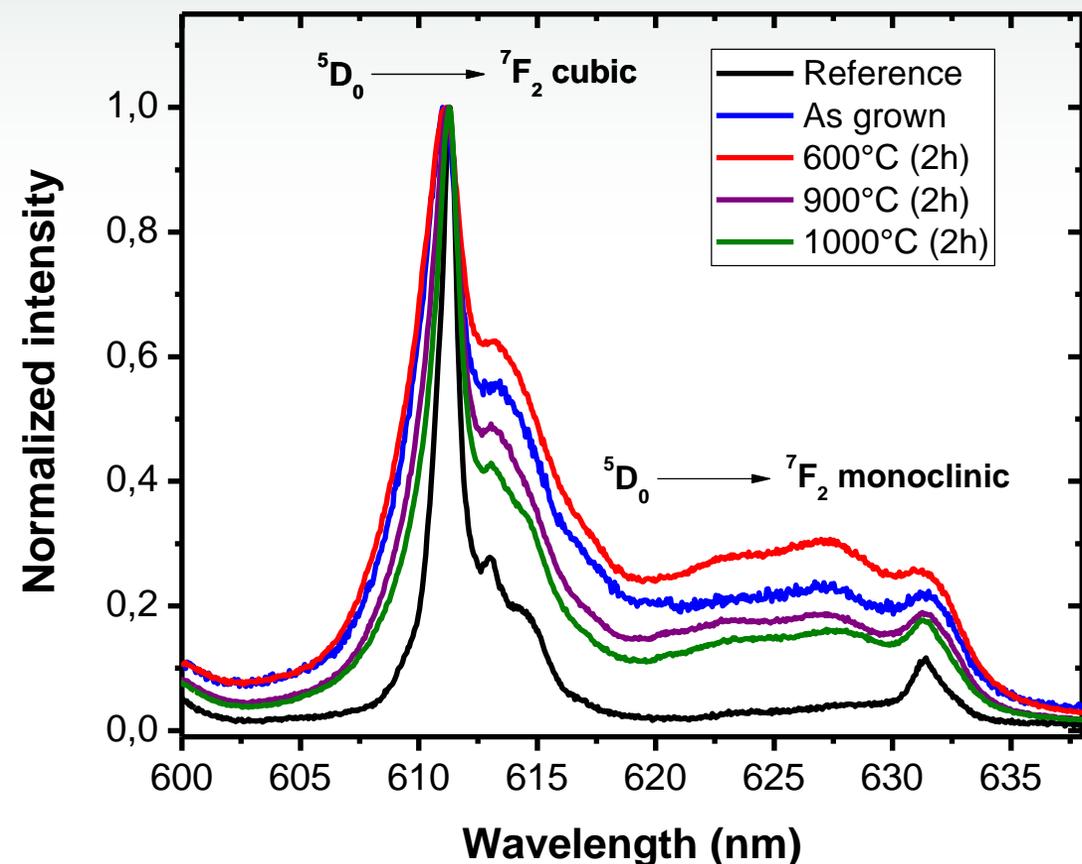
The ALD buffer layer opens the way to higher annealing steps

# II. Alternative depositions – Other substrates

- Substrate = **Sapphire (11-20)** (a-plane = blue plane)



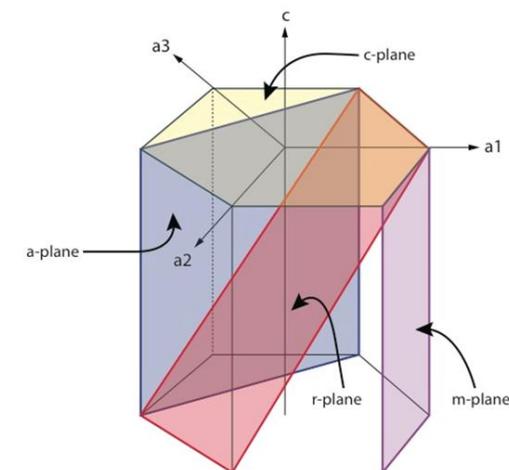
Thickness = 83 nm  
 $\text{Y}_2\text{O}_3:\text{Eu}^{3+}$  (5%)



- Improvement** of PL spectrum when the temperature increases
- No additional phases** at 1000°C

Promising PL properties at  
**1000°C => Higher temperature ?**

Hexagonal cell of sapphire



# II. Alternative depositions – Other substrates

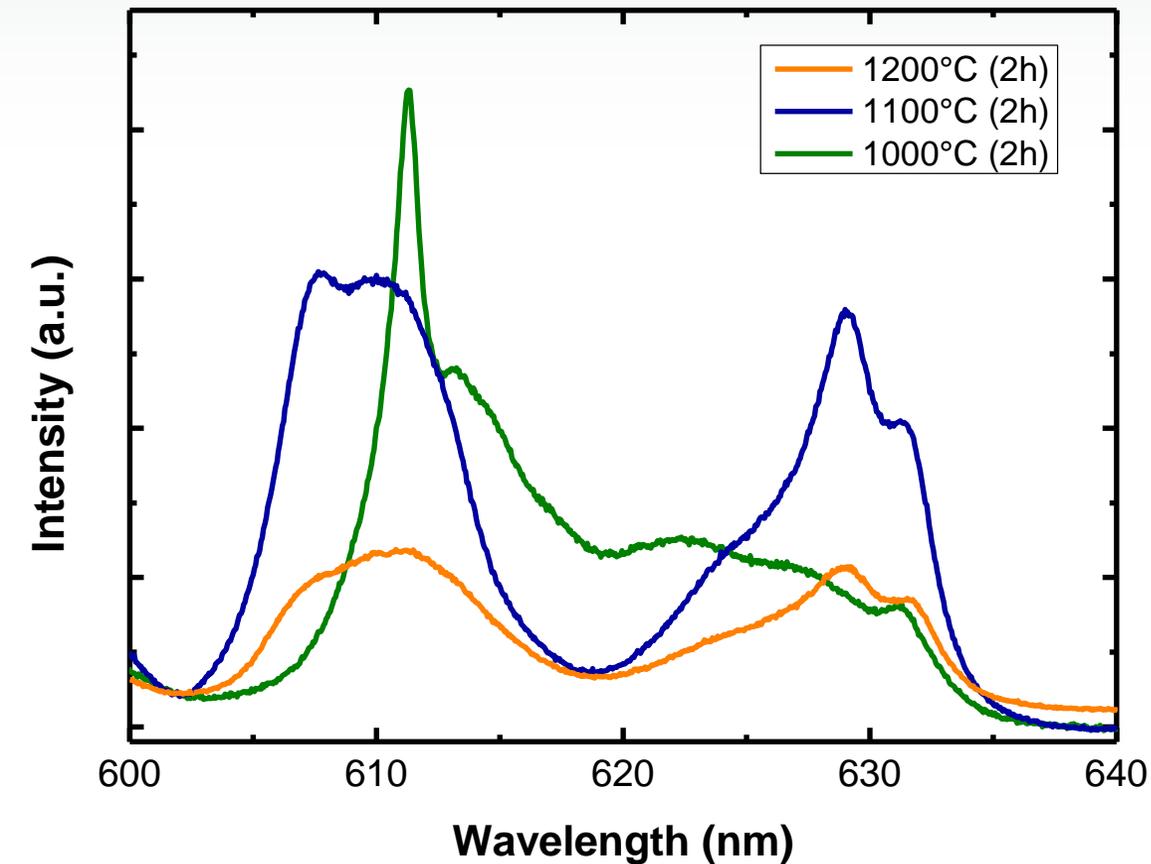
- ALD thin films on sapphire substrates annealed at 1100°C and 1200°C for 2 hours



Thickness = 83 nm  
 $\text{Y}_2\text{O}_3:\text{Eu}^{3+}$  (5%)

- Deformation of PL spectrum at **1100°C** and **1200°C**
- Formation of **new phases** at the interface

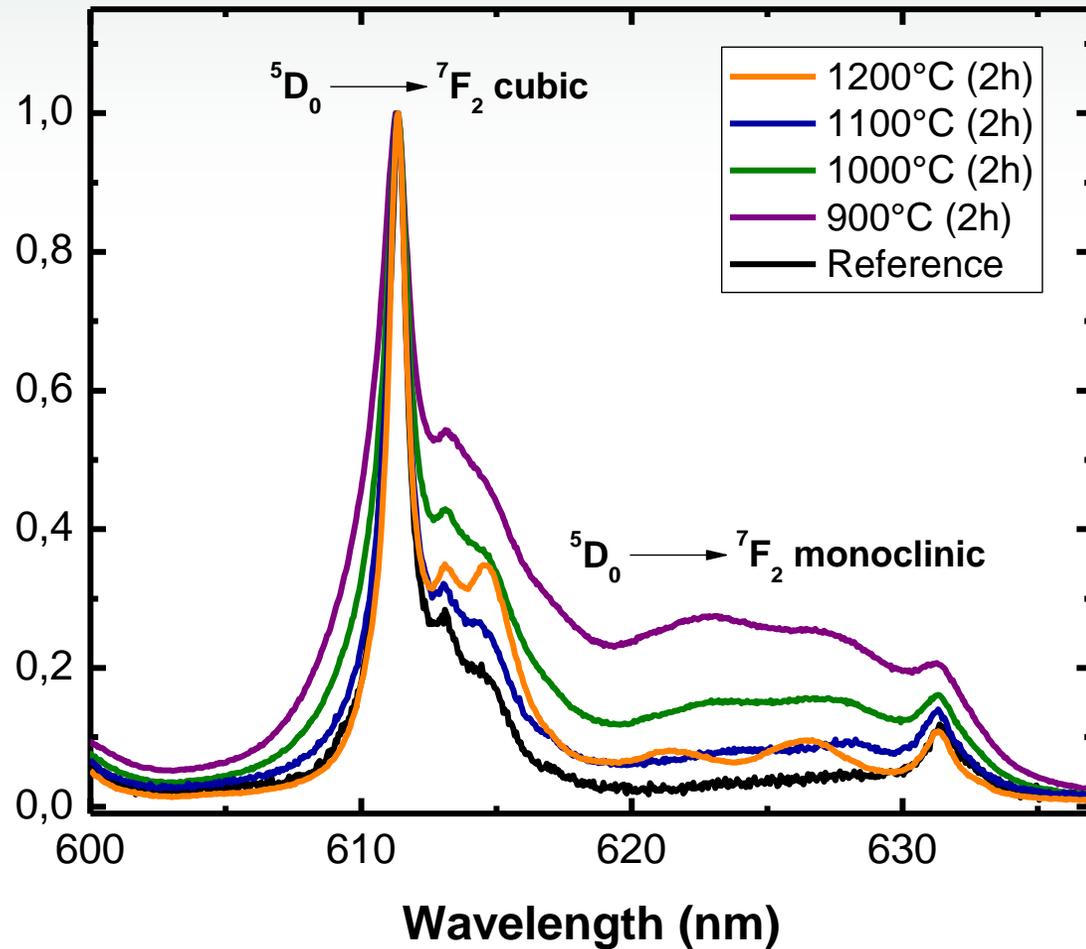
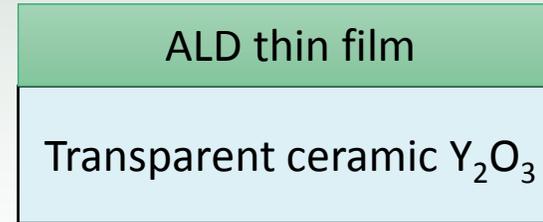
Maximum temperature for annealing step:  
**1050°C**



# II. Alternative depositions – Other substrates

- Substrate = transparent ceramic  $\text{Y}_2\text{O}_3$

Thickness = 83 nm  
 $\text{Y}_2\text{O}_3:\text{Eu}^{3+}$  (5%)



- Improvement of PL spectrum
- For  $T_{\text{annealing}} = 1100^\circ\text{C}$  and  $1200^\circ\text{C}$ , PL spectrum is **very close** to the reference
- No formation of parasitic phases

Promising PL properties with transparent ceramic  $\text{Y}_2\text{O}_3$  substrates

# Conclusions and perspectives

- Annealing step after the deposition → improved optical spectroscopic properties
- Limitation to 950°C on Si substrates → parasitic phases
- First measurement of narrow inhomogeneous linewidth on films ( $\text{Eu}^{3+} \ ^5\text{D}_0 \rightarrow \ ^7\text{F}_0$  200 GHz)
- Other substrates → higher annealing temperatures up to 1200°C
- Sapphire or transparent ceramic  $\text{Y}_2\text{O}_3$  → promising substrates

## ON PROGRESS:

- **Lifetime measurements:**
  - On other substrates
  - Improvement of lifetime up to 8 ms for 11 nm thick film (ICFO)
- Study of the emitting ions  $\text{Eu}^{3+}$  localisation on the surface
- Coherent experiment currently on thin films: **measurement of  $T_2$**

Thank you for your attention !



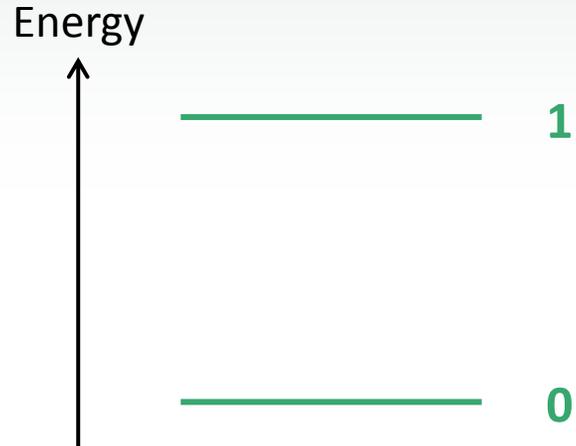
<http://www.nanoqtech.eu/>



This project has received funding from the European Union's Horizon 2020 research and innovation programme under grant agreement No 712721.

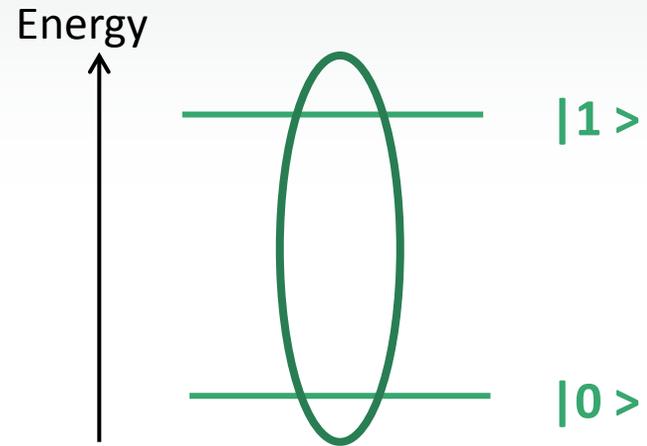
# Introduction – Quantum Properties

Classical system (bit):



=> States: 0 and 1

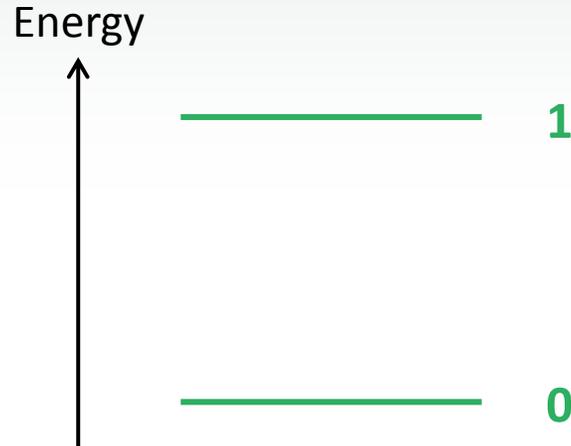
Two-level quantum system (= Qubit):



=> Superposition states:  $\Psi = a|0\rangle + b|1\rangle$

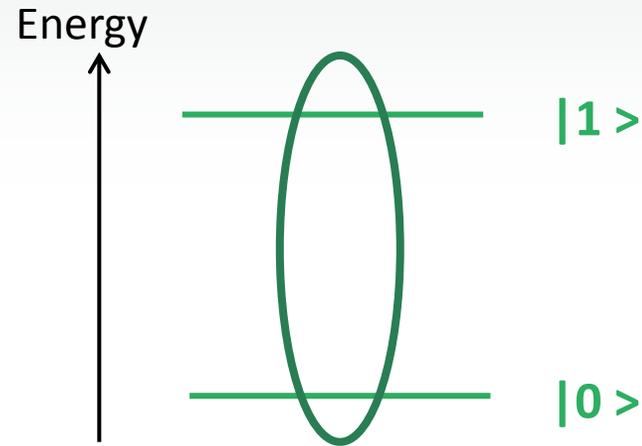
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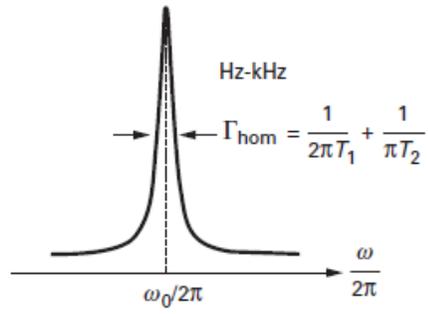


=> Superposition states:  $\Psi = a|0\rangle + b|1\rangle$

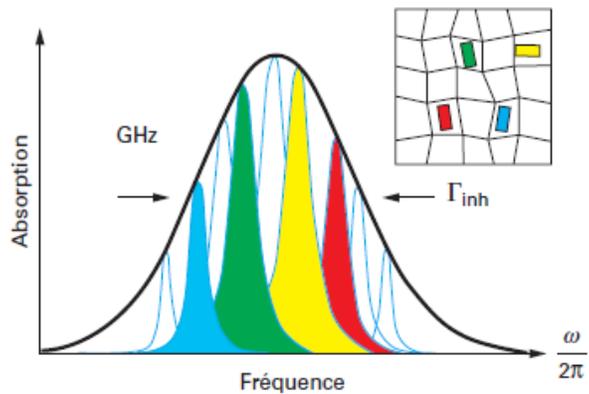
- Quantum information: **coherent superposition of two quantum states  $|0\rangle$  et  $|1\rangle$**
- **Problem** = interactions with the environment => **decoherence** (loss of quantum information)
- **Goal** = systems with coherence as long as possible (high  $T_2$ )

=> Use of rare earth ions

# Inhomogeneous Linewidth



(a) élargissement homogène provoqué par l'interaction dynamique entre l'ion  $\text{TR}^{3+}$  optiquement actif et les différentes sources de décohérence



(b) élargissement inhomogène induit par une variation d'environnement local autour de l'ion  $\text{TR}^{3+}$ . L'insert est une représentation schématique de l'environnement cristallin autour de quatre dopants différents

(1) T. Chanelière, A. Louchet-Chauvet, A. Ferrier and P. Goldner, *Cristaux et dispositifs optiques pour le traitement de l'information quantique*, Techniques de l'ingénieur (2014).

Figure 11 – Illustration des deux effets d'élargissement des raies optiques

# Alternative depositions – ALD Buffer Layer

- Cathodoluminescence spectra:

Thickness Film = 11 nm  
 $\text{Y}_2\text{O}_3:\text{Er}^{3+}$  (2%) + Buffer  $\text{Y}_2\text{O}_3$  (50 nm)  
Annealed at 950°C (2h)

